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Ambient pressure CVD of graphene on low-index Ni surfaces using methane: a combined experimental and first-principle study

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ABSTRACT

The growth of large area single-layer graphene (1-LG) is studied using ambient pressure CVD on single crystal Ni(111), Ni(110) and Ni(100). **By varying both the furnace temperature in the range of 800 - 1100 °C and the gas flow through the growth chamber, uniform, high-quality 1-LG is obtained for Ni(111) and Ni(110) single crystals and for Ni(100) thin films. Surprisingly, only multilayer graphene (M-LG) growth could be obtained for single crystal Ni(100).** The experimental results are analyzed to determine the optimum combination of temperature and gas flow. Characterization with optical microscopy, Raman spectroscopy and optical transmission support our findings. DFT calculations are performed to determine the energy barriers for diffusion, segregation and adsorption, and model the kinetic pathways for formation of different carbon structures on the low-index surfaces of Ni.

INTRODUCTION

The growth of carbon structures on different metallic/semi-metallic substrates has been extensively studied in the past decades [1-50]. Much of this research has focused on the formation of graphene on low-index nickel single-crystal surfaces, Ni(111), Ni(110) and Ni(100) [1-27, 43-46]. However, a complete microscopic understanding of the thermodynamic pathways for graphene formation on these surfaces is still lacking [15, 16, 30, 31, 46, 47, 51-57]. The growth of 1-LG on Ni(111) and Ni(110) surfaces has been reported, but similar explanations for the growth mechanisms on both surfaces is given. These explanations do not account for the distinctly different thermodynamic properties of the fcc (111) and (110) surfaces [1-27, 30, 31, 43-47, 51-57]. Advances in 1-LG growth techniques have been boosted by the isolation of 1-LG from

47 bulk graphite substrates [28], and recent research has shown the possibility of growing 1-LG and
48 multi-layer graphene (M-LG) on metals using CVD techniques without the added difficulty of ultra-
49 high vacuum environments and the subsequent transfer of such a material to dielectric substrates
50 [7-19, 29-32, 54-57]. The combination of process flexibility and high quality of the material
51 produced from these fabrication processes has enabled the integration of graphene into various
52 applications [33, 43-47, 51-57].

53
54 Although graphene has been grown successfully on a wide range of transition metals, copper and
55 nickel are the most widely used substrates [9, 43-47, 51-57]. Copper is the most frequently used
56 metal to grow monolayer graphene, since the low carbon solubility in Cu leads to a desirable self-
57 limiting surface growth of graphene [19, 32]. The same is not true for nickel (Ni), because the high
58 bulk solubility of carbon at typical high growth temperatures can result in a high rate of carbon
59 segregation and subsequent M-LG formation upon cooling. The growth of 1-LG on Cu, in general,
60 needs to be carried out under low pressure [34], further complicating the synthesis process and
61 adding to the cost of graphene production. The advantage to using nickel is that the growth of M-
62 LG can be avoided by selecting the proper growth conditions. Due to a stronger interaction
63 between graphene and Ni, only one graphene domain orientation exists for growth on Ni(111)
64 single crystals. So in this case, no tilt-grain boundaries are expected after a continuous and high-
65 quality film of graphene is formed [35].

66
67 The formation mechanisms of 1-LG are different for Cu and Ni. Growth of 1-LG in Cu is mainly
68 mediated by the adsorption of carbon atoms by the surface atoms followed by the diffusion of
69 such atoms across the surface and the formation of nucleation centers [34, 43-47, 51-57]. In Ni,
70 both bulk diffusion and surface diffusion leading to the formation of nucleation centers on the
71 surface must both be considered [1-5, 30, 34, 40, 41, 43-47, 51-57]. The growth of 1-LG graphene
72 on Ni is a crucial step toward the controlled growth of high-quality multi-layer graphene for a
73 number of technological applications [43-47, 51-57]. This motivates our study in order to further
74 optimize the growth conditions by building on the work of Seah et al., who demonstrated the
75 growth of bilayer graphene (2-LG) on Ni(111) by rapidly quenching the substrate after deposition
76 to limit the amount of carbon segregation [56].

77
78 In this work, we show that successful growth of 1-LG via ambient pressure CVD is achieved for
79 Ni(111) and Ni(110) single crystals and for Ni(100) thin films but only multilayer graphene (M-LG)
80 growth could be obtained for single crystal Ni(100). We characterize the different growth
81 mechanisms found on each orientation with optical microscopy, Raman spectroscopy and optical
82 transmission. DFT calculations are performed to provide an atomistic model of the processes
83 involved to support the experimental results. It is found that the formation of a uniform monolayer
84 on Ni single crystal substrates is epitaxially driven for the Ni(111) surface, while surface
85 thermodynamic and kinetic effects drive the formation on Ni(110) and Ni(100) by diffusion and
86 segregation of carbon atoms on Ni surfaces [2, 3, 5, 20]. The results and explanations provided
87 by this work are a step toward development of a means to control the number of graphene layers
88 formed on the surface.

89
90

91 METHODS

92

93 Experimental details

94 The Ni(111), Ni(110) and Ni(100) single crystal substrates used in this work (10mm in diameter,
95 1mm thick, 99.9995% purity) were obtained from Marketech International. The substrates were
96 electropolished further with a solution of glacial acetic acid and perchloric acid (60%) in the ratio
97 of 7:3 by volume, to produce smooth substrate surfaces. X-ray diffraction measurements for each
98 Ni substrate were performed after polishing to confirm the crystallographic orientation. The
99 Ni(100) thin films used for the comparison study are approximately 1 μ m thick. The growth of
100 graphene was performed using an ambient pressure CVD process. A 1-inch tube furnace is
101 initially preheated to the growth temperature before the introduction of the Ni substrates contained
102 within an open-ended silica tube. The substrates are then pre-cleaned by rapid heating under a
103 flow of hydrogen at 1000 sccm. The temperature is then reduced to the growth temperature and
104 methane gas at 100 sccm is added to the hydrogen flow. Exposure to methane continues for 300
105 seconds before removing the silica tube containing the substrates into a room temperature
106 environment for a fast cool down. The graphene is then transferred from the substrates using a
107 Poly(methyl methacrylate) polymer (PMMA) layer spin-coated on the surface followed by
108 electrochemical delamination of the graphene/PMMA [48 -50]. The electrolyte consists of a 1M
109 NaOH solution with a negative -10V applied on the Ni. The graphene layer can then be placed on
110 a dielectric substrate and the PMMA can be removed by immersing in acetone [17].

111

112 Computational details

113 Density Functional calculations [58] were performed with the Quantum-Espresso Package [59]
114 and the Perdew-Burke-Ernzerhof [60] Generalized Gradient Approximation as exchange-
115 correlation functional. The ultrasoft pseudopotentials of the pslibrary [61] were used with plane-
116 wave/charge density energy cutoffs of 40/320 Ry. To evaluate the interaction of carbon with each
117 Ni surface considered, the unit cells were 3x3 squares for 100, 3x2 $\sqrt{2}$ rectangles for 110, and 3x3
118 hexagons for 111. The sampling of the first Brillouin zone was performed using grids centered at
119 the Γ point, with a k-point density of 2x2x1. For the graphene monolayer coverage, the unit cells
120 of the 100/110 surfaces were increased to 4x6 and 4x5 $\sqrt{2}$, creating an average strain in the
121 graphene layer of less than 2%. Five Ni layers were used with additional 12 Å of vacuum in the
122 perpendicular direction to avoid spurious interaction between periodic images. The energy and
123 force thresholds adopted for the geometry optimizations were 0.0001/0.001 a.u., respectively, and
124 the bottom 2 Ni layers were kept frozen during ionic optimizations. Van der Waals corrections
125 within the Grimme-2D method [62] were also considered.

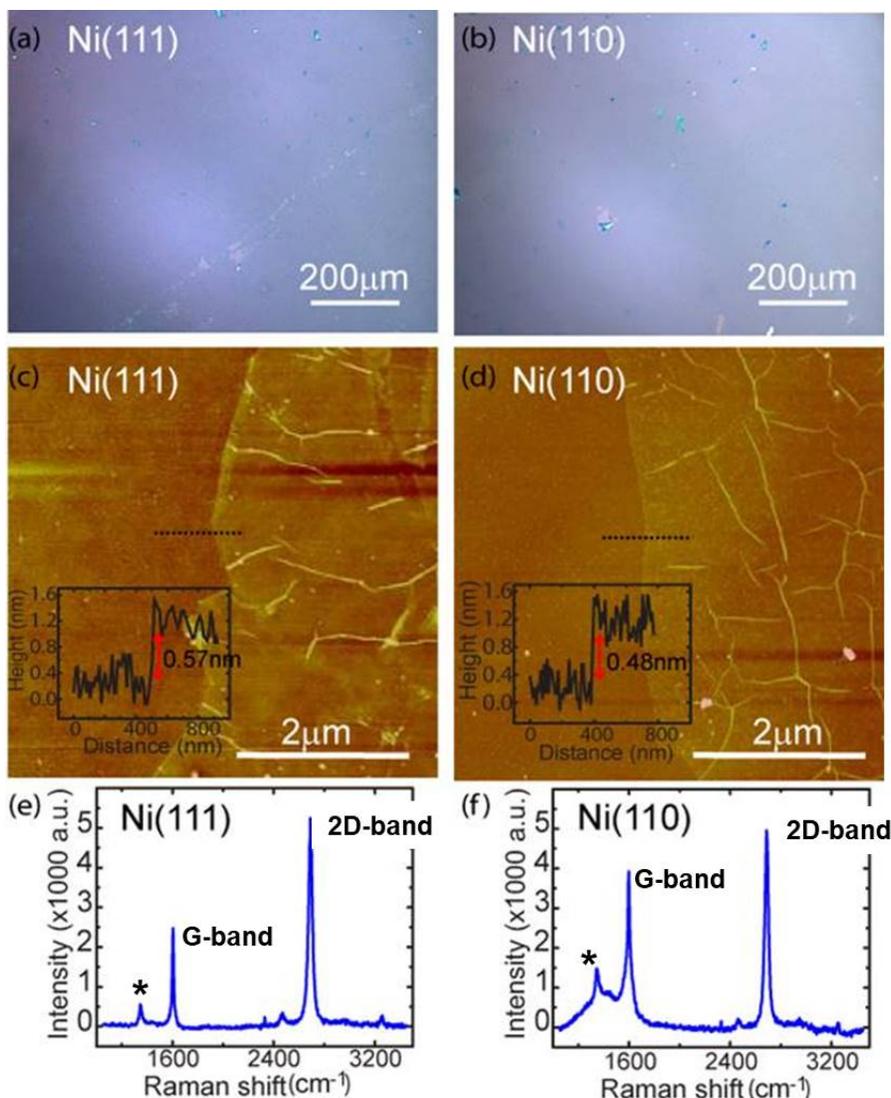
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127 RESULTS AND DISCUSSION

128

129 Figure 1 shows optical microscopy, AFM and Raman spectroscopy characterization of the 1-LG
130 films obtained for Ni(111) and Ni(110) after transferring the 1-LG films to Si/SiO₂ substrates (note
131 that 1-LG in Ni(100) thin films will be discussed later in the text). The optical images (Figures 1a
132 and 1b) show a uniform contrast similar to samples derived from Cu foils [17-19, 23]. The
133 observed optical color contrast corresponds to that estimated for 1-LG under the same theoretical
134 model as was described previously [23]. The cross-sectional thickness of the film estimated from

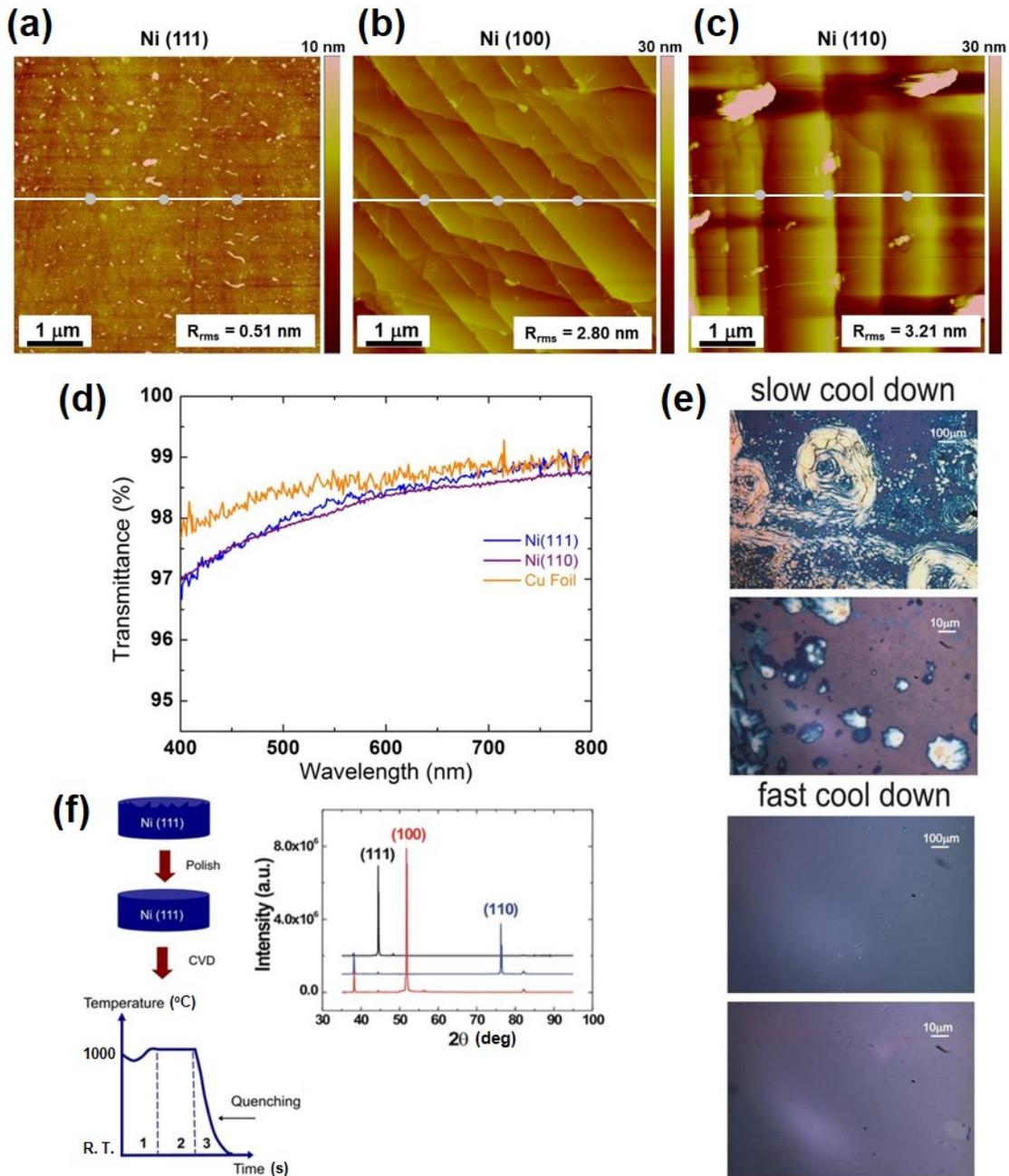
135 the AFM tapping mode images in within the expected values of 1-LG, ranging from 0.48 to 0.57
136 nm (Figures 1c and 1d). Raman spectroscopy (Figures 1e and 1f) confirms the presence of
137 graphitic carbon in its monolayer configuration. Three main features are observed with 532 nm
138 laser wavelength excitation; the D, G, and 2D Raman peaks around 1350 cm^{-1} , 1580 cm^{-1} and
139 2700 cm^{-1} . The intensity ratio between the 2D and G peak intensities (I_{2D}/I_G) close to 2 and the
140 full width at the half maximum (FWHM) of the 2D band of $\sim 30\text{ cm}^{-1}$ are spectroscopic signatures
141 of the presence of 1-LG. Differences in the D-band intensity (marked with an asterisk), suggest
142 that 1-LG grown on Ni(110) is structurally more disorganized then the corresponding film on
143 Ni(111). Further confirmation of the presence of 1-LG and of its quality when grown on Ni(111)
144 and Ni(110) catalysts was done by measuring the optical transmittance of the films over the visible
145 range (Figure 2d). The films were transferred to quartz substrates and the average transmittance
146 was measured to be approximately 97.8% for 1-LG grown on both Ni(111) and Ni(110). This value
147 is within experimental error of the expected transmission for 1-LG of 97.7% [23]. The
148 transmittance was also found to be nearly the same to that measured for 1-LG grown over a Cu
149 foil following the growth process described elsewhere [36, 37].
150



151
 152 **Figure 1.** Optical microscopy images of 1-LG grown on (a) Ni(111) and on (b) Ni(110) after transferring the
 153 1-LG layer to a Si/SiO₂ substrate. AFM images of the edge of typical 1-LG graphene films transferred to Si-
 154 SiO₂ for 1-LG grown on (c) Ni(111) and (d) Ni(110). The insets reveal the formation of 1-LG in each case. and
 155 Raman spectra are shown for 1-LG grown on (e) Ni(111) and (f) Ni(110).
 156

157 The process parameters are of significant importance for the success of 1-LG growth on Ni(111)
 158 and Ni(110) single crystals. As illustrated in Figure 2f, polishing the surface of Ni pieces (as
 159 described in the Methods section) was critical for 1-LG preparation due to the observed formation
 160 of M-LG under the same processing conditions on samples rougher than a few nanometers.
 161 Formation of M-LG can be attributed to the preference of graphene formation on Ni step edges,
 162 which are more abundant on rougher crystalline surfaces [25, 38, 39]. Growth on a rough surface
 163 results in the overlap of islands originating from neighboring step edges [1-5, 35, 38]. Figures 2(a)
 164 through (c) show Atomic Force Microscopy (AFM) images of clean and polished surfaces for
 165 Ni(111), Ni(100) and Ni(110) before graphene growth. The surface roughness is the largest for
 166 Ni(110) and the smallest for Ni(111). None of the surfaces prepared using our method were rough
 167 enough to prevent monolayer growth. The inset in Figure 2f shows the X-Ray Diffraction (XRD)

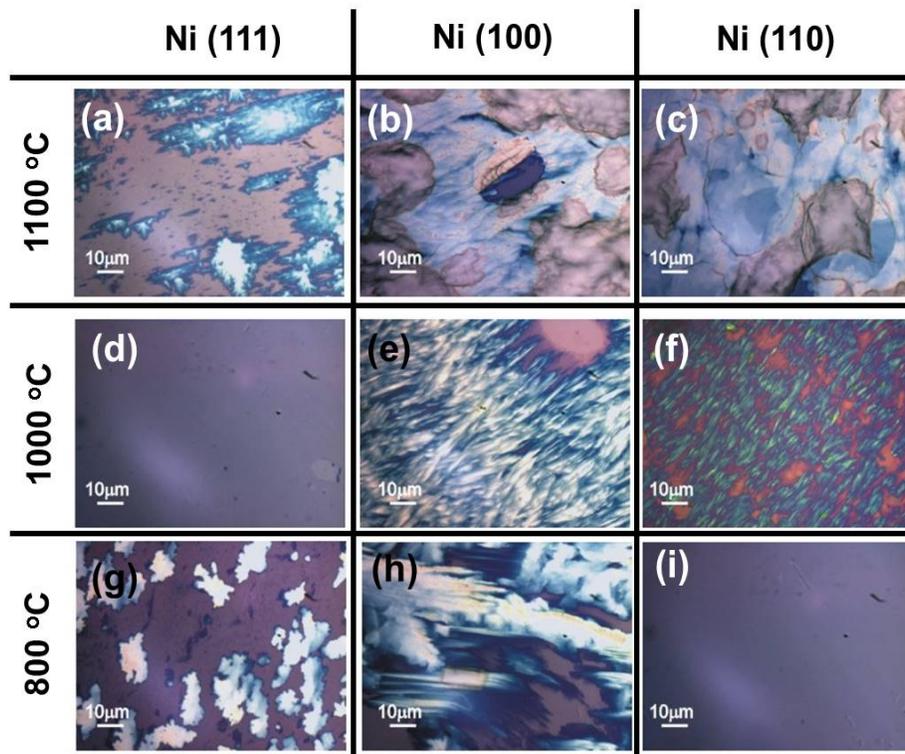
168 measurements taken from the Ni(111), Ni(110) and Ni(100) single crystals, confirming their
 169 crystallographic directions.



170
 171 **Figure 2.** Atomic Force Microscopy (AFM) images of clean and polished surfaces for (a) Ni(111), (b)
 172 Ni(100), and (c) Ni(110) before graphene growth. The solid lines and spaces between bullets indicated,
 173 respectively, where a surface profile line was taken and regions where roughness analyses were
 174 performed. The roughness (R_{rms}) reported in the bottom right corner is an average of values taken in several
 175 different regions. (d) Optical transmittance across the wavelength range of 400-800 nm for 1-LG films grown
 176 from Ni(111) (blue), Ni(110) (purple) and Cu foil (orange). (e) Images of samples obtained for Ni(111) using
 177 fast and slow cool down from $T=1000 \text{ }^\circ\text{C}$. Fast quenching produces a more continuous film of 1-LG, while
 178 slow quenching produces an inhomogeneous film composed of few layer flakes and fragments. (f)

179 Schematic of the processing steps for growing 1-LG from Ni single crystal. R.T. stands for room
 180 temperature. The inset shows the XRD measurements of the Ni(111), Ni(110) and Ni(100) single crystals.
 181

182 The cooling rate for temperature quenching of the Ni plays a significant role in the crystalline
 183 structure of the resulting sample. A fast cool down prevents the formation of a graphite phase
 184 after the monolayer forms on the Ni surface (bottom panel in Figure 2e). Slow cooling results in
 185 films consisting mostly of M-LG (top panel in Figure 2e). In addition, the selected growth
 186 temperature (T) must be correct to achieve 1-LG formation on Ni. For the same gases and flow
 187 rates ($H_2=1000$ sccm, $CH_4=100$ sccm) and growth time ($t=5$ min), the optimum growth
 188 temperature T depends on surface orientation. We found that 1-LG on Ni(111) is formed at
 189 $T=(1000\pm 1)$ °C. In contrast, M-LG is formed on the Ni(110) and Ni(100) surfaces, as shown in
 190 Figures 3d, 3e and 3f. For a growth temperature of $T=(800\pm 1)$ °C, 1-LG is formed on Ni(110) and
 191 M-LG is formed on Ni(111) and Ni(100), as shown in Figures 3g, 3h and 3i. For the experimental
 192 conditions investigated in this work, 1-LG was not formed on a Ni(100) single crystal, but 1-LG
 193 was formed on Ni(100) thin films. For the deposition temperatures investigated below 800°C, no
 194 ordered carbon structures were formed on any of the Ni surfaces, independent of their
 195 crystallographic orientation. Table 1 summarizes the results for Ni single crystals.
 196



197
 198 **Figure 3.** Optical absorption images of graphene grown on the Ni(111), Ni(100) and Ni(110) at
 199 temperatures of 800, 1000 and 1100 °C. Multi-layer graphene is obtained in all cases, except for (i) Ni(110)
 200 at 800 °C and (d) Ni(111) at 1000 °C, where 1-LG is obtained.
 201
 202

203 **Table 1.** Summary of the growth of carbon structures at different temperatures and different crystallographic
 204 directions using gas flow rates of 1000 sccm for H₂ and 100 sccm for CH₄. 1-LG is single-layer graphene
 205 and M-LG is multi-layer graphene.
 206

	Ni(111)	Ni(110)	Ni(100)
1100 °C	M-LG in single crystal	M-LG in single crystal	M-LG in single crystal
1000 °C	1-LG in single crystal	M-LG in single crystal	M-LG in single crystal and 1-LG in thin film
800 °C	M-LG in single crystal	1-LG in single crystal	M-LG in single crystal
750 °C - 790 °C	None	None	None

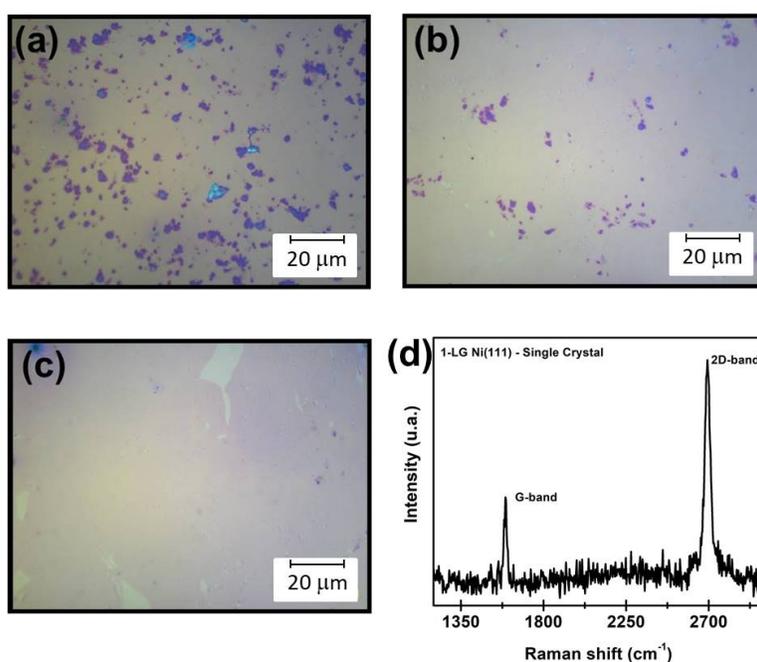
207
 208
 209 **Growth of 1-LG on Ni(111)**
 210 Nickel crystals are Face Centered Cubic (FCC) structures with a bulk lattice parameter of 3.52 Å.
 211 Ni(111) has a surface lattice parameter of $a_{\text{Ni}(111)} = 2.49 \text{ \AA}$ while 1-LG is a nearly perfect match
 212 with $a_{\text{1-LG}} = 2.46 \text{ \AA}$ [1-5]. Compared to the other two orientations, Ni(110) and Ni(100), Ni(111)
 213 has the highest atomic packing density [41, 63] and the smallest surface energy, $S_{\text{Ni}(111)} = 1606$
 214 ergs.cm^{-2} versus $S_{\text{Ni}(110)} = 2057 \text{ ergs.cm}^{-2}$ and $S_{\text{Ni}(100)} = 1943 \text{ ergs.cm}^{-2}$ [1-5, 64]. Since the surface
 215 energy is related to the strength of the C-Ni interaction, we expect that the carbon adsorption
 216 energy and energy barriers E_{across} for the diffusion across the surface [40-42, 65] to be related to
 217 $S_{\text{Ni}(111)}$, which means that they should be lower in this (111) face. Diffusion of carbon atoms will
 218 also be dependent on its surface mean-free path. If the density of C atoms increases, the mean
 219 free path decreases, making diffusion less likely since dimers have reduced mobility. The C
 220 deposition rate is proportional to the reactivity rate of methane and is the smallest on Ni(111) at
 221 all temperatures [1-5].
 222

223 For Ni(111) 1-LG was obtained at $T=(1000\pm 1) \text{ }^\circ\text{C}$, while M-LG was obtained at $T=(1100\pm 1) \text{ }^\circ\text{C}$
 224 and at $T=(800\pm 1) \text{ }^\circ\text{C}$ and no carbon structure formation was observed for temperatures below
 225 $(790\pm 1) \text{ }^\circ\text{C}$ (we have studied temperatures between 750 °C and 800 °C in steps of 10 °C). At the
 226 optimum growth temperature of $(1000\pm 1) \text{ }^\circ\text{C}$, the driving phenomena behind the growth are
 227 balanced, mainly the deposition rate, diffusion across the surface, diffusion into the bulk and
 228 segregation during cool down. An additional factor is that CH₄ reactivity is above a minimum
 229 threshold at this temperature, but this is already the case at 800 °C (see Table 1).
 230

231 At 800 °C, bulk diffusion is significantly lower compared to 1000 °C and, consequently, the
 232 segregation during the fast cool down is inhibited. Diffusion of carbon atoms into the bulk at 1000
 233 °C and the limited segregation during rapid cooling control the density of carbon atoms for the
 234 Ni(111) surface, thereby allowing 1-LG formation. At higher temperatures such as 1100 °C, the
 235 probability of carbon atom diffusion across the surface and the probability of carbon atom diffusion

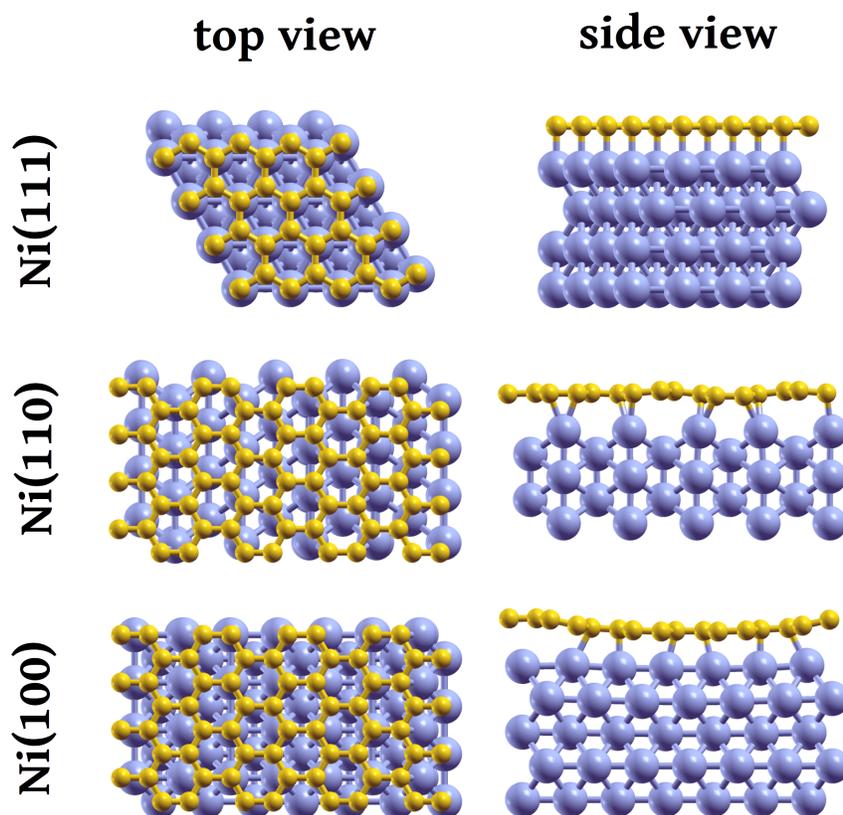
236 into the bulk are approximately equal and the flux of carbon atoms diffusing into the bulk is larger.
237 In addition, cooling from 1100 °C takes longer, resulting in increased carbon segregation during
238 the cooling down process, so M-LG was preferentially obtained on Ni(111).
239

240 By changing process parameters for temperatures between 780 °C and 1000 °C, the growth of
241 monolayers on Ni(111) is possible. Below 1000 °C, the deposition rate and the sticking coefficient
242 of carbon on the Ni substrate decrease, so obtaining M-LG between 1000 °C and 780 °C probably
243 means that the flow of CH₄ is still too high in such cases, even though the deposition rate
244 decreases (diffusion into the bulk is increasingly suppressed as the temperature decreases). So
245 by substantially decreasing the CH₄ flow, 1-LG is expected. In Figure 4(a)-(c), it is demonstrated
246 that mostly 1-LG can be obtained at 900 °C if the CH₄ flow is reduced from 100 to 50 sccm, while
247 the H₂ flow is kept at 1000 sccm and a rapid cool down is used. Figure 4(d) shows the Raman
248 spectrum for the 1-LG grown under such conditions.
249



250
251 **Figure 4.** Optical images of the graphene films obtained from Ni(111) at T=900 °C and gas flows of H₂ =
252 1000 sccm and (a) CH₄ = 100 sccm, (b) CH₄ = 75 sccm and (c) CH₄ 50 sccm. 1-LG is formed when the
253 flow of methane is decreased from 100 sccm to 50 sccm. (d) Raman spectrum for the 1-LG shown in (c).
254

255 Our computer simulations suggest that 1LG on Ni(111) has a planar structure, with half of the
256 carbon atoms attached to an on-top position and the other half attached to a hollow-hcp position,
257 as shown in Figure 5. Although we present this structure as the most stable, there is still
258 disagreement about the best atomic arrangement of graphene on Ni(111). In fact, it has been
259 shown that more than one structures may coexist [9, 66, 67], due to the very low energy difference
260 between them. The structural and energetic parameters are listed in Table 2.
261



262
263 **Figure 5.** 1-LG on nickel, in its optimized configuration. In yellow, carbon atoms and in blue, nickel.
264

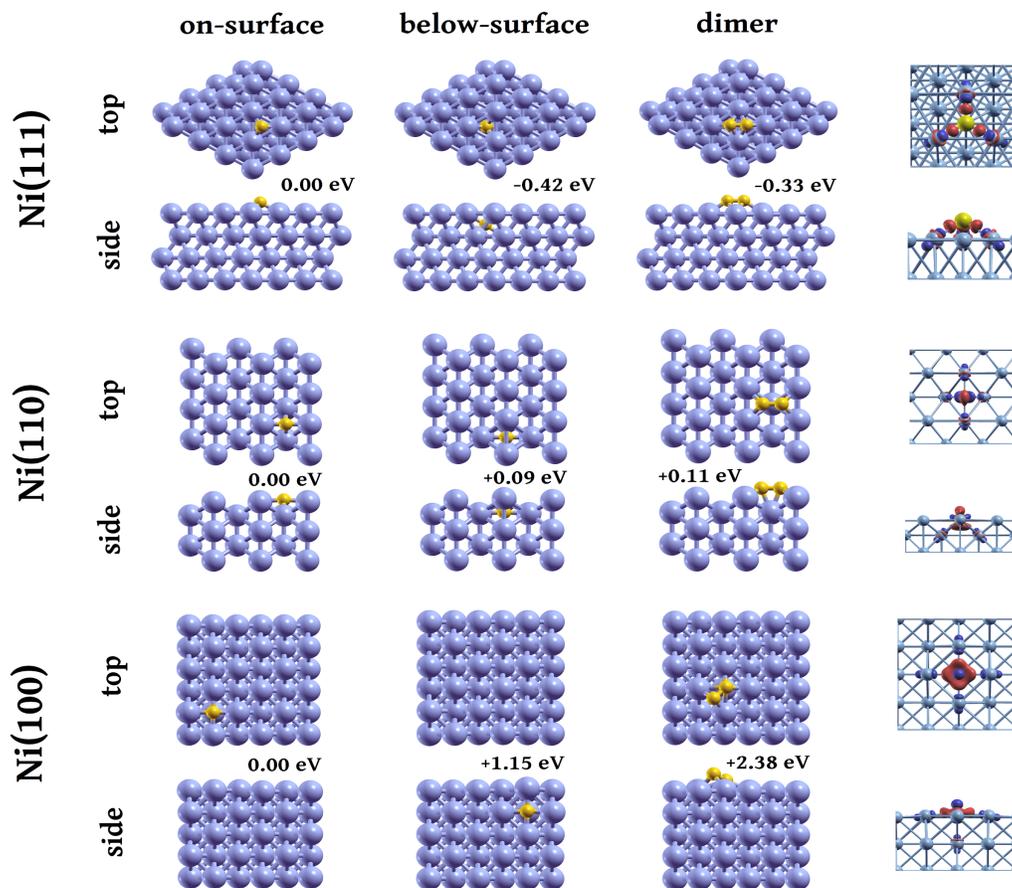
265 **Table 2.** Energetic and structural information of 1-LG on different crystal planes as obtained by DFT
266 calculations, shown in Fig. 05. The values show the average adsorption energy by atom, the average
267 carbon-surface distance and the maximum buckling on the graphene layer.
268

	E_{ads} (meV.at ⁻¹)	$d_{\text{graph-surf}}$ (Å)	buckling (Å)
Ni(111)	164	2.11	0.00
Ni(110)	209	2.03	0.29
Ni(100)	180	2.13	0.69

269
270
271 **Suggested model for carbon growth on Ni(111)**

272 We have calculated the adsorption energy of a single carbon atom on a perfect Ni(111) surface,
273 emulating the low concentration regime, corresponding to the initial stages of growth (see Figure
274 6). Nearly all generated carbon will diffuse laterally until a dimer is formed. Trimers and tetramers
275 are less stable than dimers, so probably the first stages of the growth will involve only dimers.
276 The best site for carbon adsorption on the surface is on a hollow site, in agreement with theoretical
277 results from the literature [68, 69] (for more information about the structures and the way of
278 calculating the adsorption energies, please see the [Supplemental Material \[70\]](#)). The carbide

279 position, corresponding to carbon absorption is more stable by 0.42 eV. For a second C atom,
 280 there is a 0.33 eV gain in forming a dimer, instead of adsorbing far away from the first C atom. All
 281 the adsorption energies for a single carbon atom, as well as the structural parameters for the
 282 configurations, are presented in Table S1. To obtain an entire picture of the processes involved
 283 in the first stages of carbon deposition, we have also evaluated the diffusion barrier for diffusion
 284 across (E_{across}) and into the surface (E_{into}), as well as dimer diffusion across the surface. Figure
 285 7a illustrates the main paths considered and Figure 7b quantifies them, showing that E_{across} barrier
 286 is less than half of E_{into} .
 287

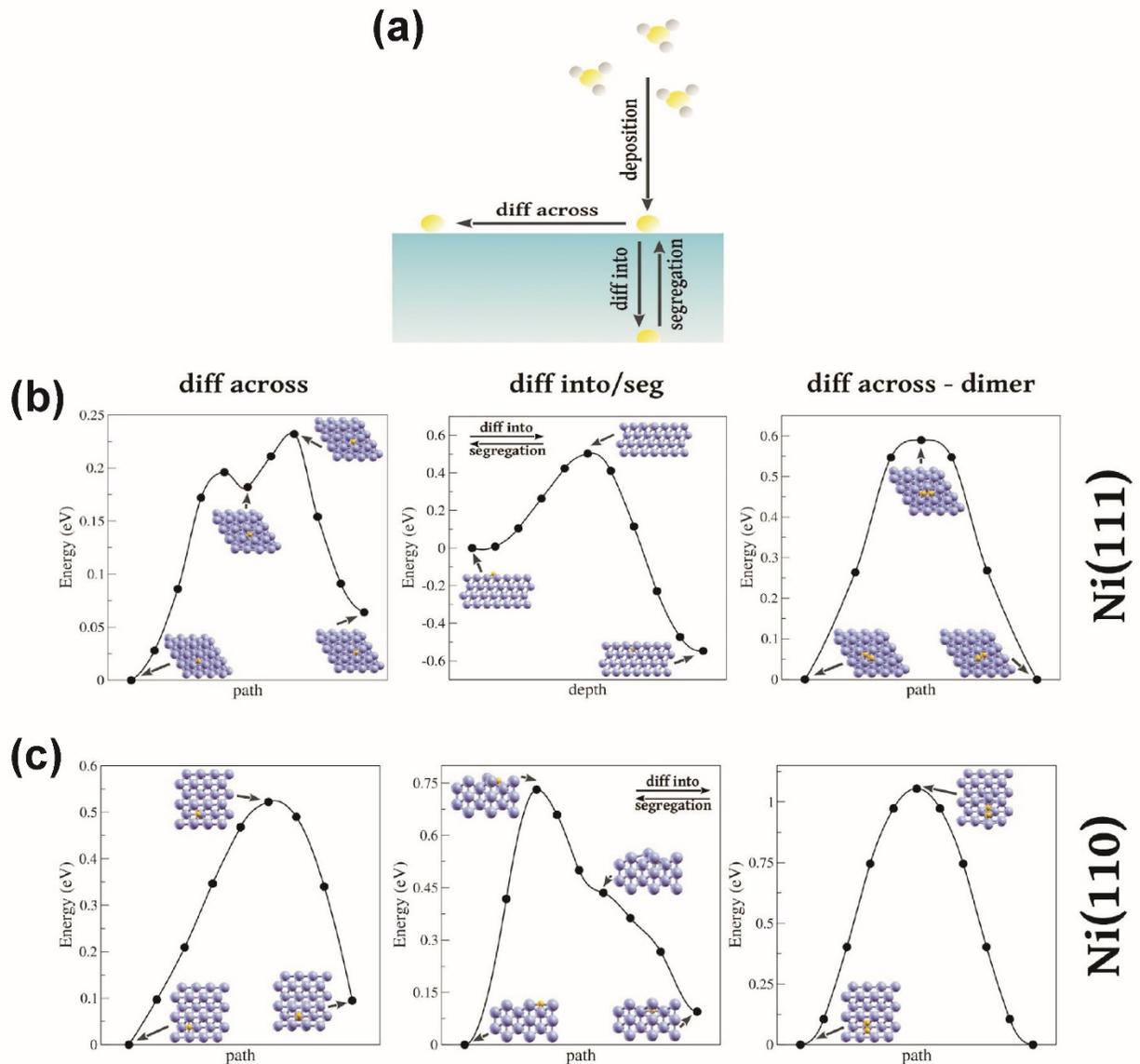


288
 289 **Figure 6.** The most stable sites for (from left to right): carbon adsorption, carbide formation, and dimer
 290 formation on different Ni crystal planes. The color code is the same as in Figure 5. The relative adsorption
 291 energies for each surface are displayed, and in the case of dimers, the value corresponds to the energy
 292 variation with respect to the adsorption of two isolated C atoms. On the right, the charge density difference
 293 for single atom adsorption is shown. In these plots, red/blue means electron accumulation/depletion.
 294

295 With these experimental and theoretical results in mind, we propose a possible scenario for
 296 graphene formation on Ni(111). At the low coverage regime, the incoming C atoms should adsorb
 297 at the surface and diffuse across the Ni surface at a much higher rate than into the Ni bulk. If the
 298 deposition rate is large enough and the temperature is low enough to inhibit diffusion into the bulk,
 299 then the adsorbed C atoms should preferentially form dimers. Dimers are more stable than
 300 monomers, and it is nearly impossible for a dimer to diffuse into the bulk. Dimers may form trimers

301 with incoming C atoms and the dimers can also diffuse across the surface with a somewhat higher
302 activation energy of around 0.6 eV. Formation of a monolayer will depend mostly on a delicate
303 balance of the deposition rate and the temperature. We also note that the formation of a carbon
304 cluster on Ni(111) is favored by symmetry (see Figure 6), since Ni(111) has a surface with
305 hexagonal regularity and a lattice parameter very close to that of 1-LG.
306

307 Following the work by Ozcelik [31], it is possible that the atoms attached to the edges of the
308 clusters will form pentagons and heptagons that will grow and heal themselves forming hexagons
309 by a Stones-Wales-Thrower mechanism. The connection among the several nucleation centers
310 is likely to occur through this process. From these considerations, Ni(111) is expected to provide
311 the best quality graphene. At low growth temperature (800 °C), surface diffusion of carbon atoms
312 dominates, so eventually M-LG will grow. For higher temperatures (1000 °C), bulk diffusion
313 dominates and less surface carbon concentration is expected. Dimer diffusion will become more
314 probable, and dimers would connect and generate 1-LG. Finally, if the temperature is too high
315 (1100 °C) the fast reactivity of CH₄ will generate a higher carbon concentration at the surface, so
316 M-LG will grow. Although our calculations suggest that the growth of nucleation centers goes by
317 the formation of dimers, the formation of nucleation centers by dimers was unclear until recently:
318 Patera *et al.* [71] demonstrated via experiments and DFT calculations that the 1-LG growth
319 process occurs by the addition of carbon lines parallel to the graphene edge always involving a
320 kink site and a Ni adatom. The participation of Ni adatoms is energetically favored since it reduces
321 the rate limiting energy barriers by approximately 35% (according to their calculations it lowers
322 from 2.46 to 1.61 eV). Therefore, Ni adatoms spontaneously bind to kink sites in the graphene
323 edge, and act as single atom catalysts where carbon atoms stabilize the attachment of Ni
324 adatoms. This consequently promotes the addition of carbon atoms in the edge formation. Based
325 on our calculations we propose that, even though the range of temperatures in our experiments
326 is different, the formation of graphene domains follow the same trends.



328
 329 **Figure 7.** Diffusion of carbon on a nickel surface. In (a) all the processes involved at the first stages of
 330 graphene growth on nickel are depicted. In (b) and (c) the kinetic barriers for diffusion across and into (or
 331 segregation, in reverse) for a single carbon atom and diffusion across for a dimer, on the 111 and 110
 332 planes, are shown. The color code is the same as in Figure 5. For the case of Ni(100) all the barriers are
 333 higher than 1 eV, so they are not shown.

334

335 Growth of 1-LG on Ni(110)

336 C-C bonds are expected to lead to the formation of monolayer graphene on the 110 surface,
 337 however a complete understanding of the routes leading to the formation of a stable and large
 338 area of a graphene monolayer has been elusive [1-5,13-15,38, 43]. The Ni(110) surface has the
 339 lowest atomic packing density. The C deposition rate ($R_{Ni(110)}$) and the surface energy for Ni(110)
 340 are the largest compared to the 111 and 100 directions. On Ni(110) with gas flows of 1000 sccm
 341 for H_2 and 100 sccm for CH_4 with rapid quenching after deposition, 1-LG was obtained at (800 ± 1)
 342 $^{\circ}C$, M-LG was obtained at (1000 ± 1) $^{\circ}C$ and (1100 ± 1) $^{\circ}C$ and no carbon structure formation was
 343 observed below 790 $^{\circ}C$ (see Table 1).

344
345 Films of 1-LG will be incommensurate with the Ni(110) surface and this results in Moiré patterns
346 [13, 14]. In addition, the carbon nucleation sites have different orientations, producing multiple
347 graphene domains. As a consequence, graphene in Ni(111) is expected to have poorer quality
348 relative to that grown on the 111 plane. The Raman spectrum in Figure 1f shows a significant D-
349 band intensity for 1-LG grown on Ni(110), while Figure 1e shows a very weak D-band intensity
350 for 1-LG grown on Ni(111). Our computer simulations suggest that the graphene monolayer
351 formed on a perfect Ni(110) surface is not planar, but has a buckling due to the different C-Ni
352 bonds formed due to the mismatch between the two structures. The best configuration found is
353 shown in Figure 5, and the energetics and structural data are shown in Table 2. A complete model
354 that describes the dynamics of 1-LG formation in Ni(110) is yet to be developed, but recent
355 information regarding diffusion and segregation may further this effort [1,15].
356

357 **Suggested Model for carbon growth on Ni(110)**

358 Our computer simulations results suggest that carbon atoms would preferably attach to a bridge-
359 001 site (see Figures 6 and S1 for details). The carbide formation is slightly disfavoured, but only
360 by 0.09 eV. On this plane, the energy barriers to diffuse across the surface or into the bulk are
361 closer (0.53 eV for across and 0.72 eV for into), and we expect these two processes to compete
362 more compared to the 111 case. Paths and kinetic barriers are shown in Figure 7c. The arrival of
363 a second C atom creates a competition between dimer formation and isolated adsorption since
364 they have very similar energies, as shown in Figure 6. Trimers and tetramers are less stable than
365 dimers and are not likely to be formed. Therefore, at the low coverage regime, the 110 face shows
366 more balanced thermodynamics, with dimer formation, diffusion and segregation in close
367 competition with each other.
368

369 The incommensurability of graphene with the substrate may reinforce growth through the healing
370 mechanism of pentagons and heptagons [31]. On the other hand, the lack of hexagonal symmetry
371 of this face may result in graphene domains growing from different nucleation sites joining with
372 different orientations. As a consequence, we would expect graphene with poorer quality relative
373 to the 1-LG grown on the 111 direction. Electrical measurements should also confirm these
374 statements about the quality of the 1-LG grown on the different Ni surfaces. However, to the best
375 of the authors' knowledge, there are no such measurements in the literature focusing on the
376 quality of graphene formed in each direction.
377

378 In summary, we suggest that a carbon on the 110 plane can diffuse across the surface or into the
379 bulk with nearly the same likelihood because the barriers for both processes are similar. At 800°C
380 this balance allows the surface to have a moderate carbon concentration with enough time to
381 order. Also the bulk should not saturate, and segregation is not likely to occur. Dimers are slightly
382 less stable than monomers, so atomic carbon is available to diffuse into the bulk while carbon
383 concentration is low. After reaching a threshold coverage, carbon atoms dimers will be more
384 prevalent and graphene would grow. The symmetry of the plane does not favor the formation of
385 highly ordered graphene. When temperature is increased (1000°C) the reaction rate of CH₄
386 increases and the resulting high carbon concentration produces M-LG.
387

388 **Growth of M-LG on Ni(100)**

389 Epitaxial growth of 1-LG is more complicated than the previous cases due to the larger mismatch
390 between graphene and Ni(100) surface. The C deposition rate ($R_{\text{Ni}(100)}$) and the surface energy
391 for Ni(100) are smaller compared to the 110 direction but are larger compared to the 111 direction.
392 Our computer simulations predict that, if formed, a graphene layer on the Ni(100) surface would
393 not remain planar, but would have a large corrugation due to the mismatch between the two
394 structures (graphene has a honeycomb structure while the Ni(100) surface has a square
395 symmetry). These undulations prevent some of the carbon atoms to be directly linked to the
396 metallic surface, as shown in Figure 5. Theoretical simulations from the literature [72] have also
397 obtained these undulations, that may vary in amplitude between 0.2 Å to 1.0 Å depending on the
398 graphene position and orientation with respect to the Ni surface, and also the size of the unit cell
399 used in the simulation. In our experiments, even though we tested different growth parameters,
400 such as temperature and gas flow, 1-LG was not obtained on Ni(100). To grasp why graphene is
401 not formed, we need to understand better how carbon interacts with the Ni atoms at the surface
402 when adsorbed or segregated.

403
404 We performed DFT calculations of the adsorption energy of individual carbon atoms on the 100
405 plane, finding that the most stable site is the hollow one (see Figures 6 and S1 for details).
406 Observing the charge density difference plots (displayed in Figure 6) and Bader charges for the
407 three surface planes (-0.70 for C on Ni(111), -0.83 for C on Ni(110) and -0.99 for C on Ni(100)),
408 we can deduce that the C-Ni bonds on the 100 face are stronger and more localized than on the
409 111 and 110 planes. This charge localization would inhibit dimer formation, due to the fact that
410 this new C-C bond would weaken the strong C-Ni and Ni-Ni already existing bonds. This disruption
411 in the nickel orbitals (related to spin unpairing) would take the Ni crystal out of its energy minimum
412 [1-5, 28, 38, 40, 41]. Our calculations show that the dimer formation is highly unlikely at low
413 coverages (dimer formation is 2.38 eV higher in energy than two carbon atoms separately
414 adsorbed), and this is also prevented by symmetry.

415
416 The large adsorption energy difference between sites (all listed in Table S1) makes lateral
417 diffusion unlikely, with barriers in the order of 2.17 eV. Although the 100 surface is more open
418 than the 111 plane, diffusion into the bulk is less likely in the low coverage regime (below 0.5
419 monolayer coverage, where C-C bonds should be disfavored) because the carbide phase with
420 the carbon atom below the surface is very unstable (1.15 eV higher in energy than a carbon on a
421 surface hollow site). At approximately 1 monolayer coverage or larger, carbon may enter the
422 surface and create lattice disorder. Dimers are not likely to form as evidenced by prior work
423 investigating segregation of carbon on Ni(100) surfaces that show monomers are well described
424 by the Langmuir model where only non-interacting solute atoms are taken into account [1-5, 28,
425 38, 40, 41, 45]. According to Porter et al. [1], segregation of C atoms to the surface of Ni(100) is
426 reversible at monolayer coverages, confirming that C atoms at the surface are weakly interacting
427 with each other.

428
429 Most theoretical predictions [1-5, 9, 20, 30, 31] point out that Ni(100) is unlikely to allow any
430 formation of an organized carbon structure. At high carbon saturation levels, occurring at
431 sufficiently high temperatures (above 800 °C in this work), M-LG structures are obtained on this

432 face. Indeed, after CH₄ breaking at the 100 surface, the carbon atoms attach strongly on the
433 hollow sites (tetra-coordinated). These bonds are highly localized. Diffusion across and into are
434 not likely to occur in the low coverage regime, because the barriers are very high. Dimers would
435 not form, because the C-Ni bond is too strong when compared with a possible C-C bond. As the
436 carbon concentration increases all the processes would start to compete. Some of the atoms
437 would diffuse into the surface, and others would attach to the pre-existing Ni-C layer. When
438 saturation is reached, segregated C atom would attach to the surface carbon layer from below.
439 The plane symmetry and the high carbon concentration (even at low temperatures) will favor the
440 precipitation of M-LG.

441

442 **Growth of 1-LG on Ni(100) Thin Films**

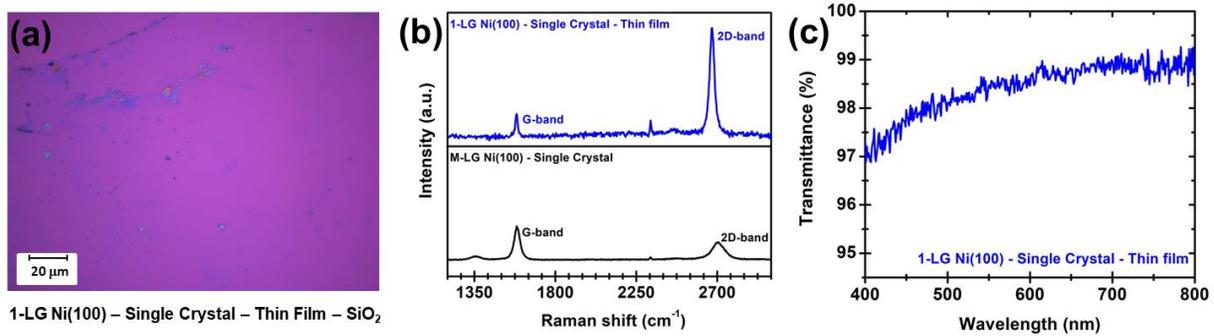
443 Rasuli et. al [15] performed theoretical calculations simulating CVD growth of graphene on
444 Ni(100). They predict that by varying the flux of gases and temperatures it is possible to grow
445 high-quality monolayer graphene. In the present work, we varied the temperature up to (1100±1)
446 °C and varied the gas flux but we did not observe any carbon monolayer structure formation for
447 Ni(100) single crystals. A possible explanation for predicted monolayer formation (and not
448 multilayer formation) could be related to the fact that only four layers of Ni were used to represent
449 the substrate, limiting a complete description of the diffusion into the substrate and segregation
450 that might occur at these temperatures. In their calculation, strong Ni-C interactions may be
451 underestimated at the low coverage regime, as opposed to our findings that show these are
452 essential for predicting the formation of carbon structures using a Ni(100) catalyst.

453

454 More recently, Zou *et al.* [72] demonstrated via experiments the successful growth of 1-LG for
455 Ni(100) single crystals and on Ni(100)-oriented domains of 1µm thick polycrystalline Ni(100). Their
456 DFT calculations assume the interaction of a pre-existent monolayer with the Ni surface and are
457 in good agreement with ours, as shortly described above. These experiments [72] motivated us
458 us to perform experiments on 1µm-thick Ni(100) thin films. We applied the same growth conditions
459 as for the Ni(100) single crystals, and for the same gases and flow rates (H₂=1000 sccm, CH₄=100
460 sccm) and growth time (t=5 min), we successfully obtained 1-LG on Ni(100) films using the rapid
461 cool down procedure from a growth temperature of 1000 °C. Note that our results complement
462 their findings since the growth temperature and the carbon source used here are different: their
463 growth temperatures range from 400 to 600 °C and they use ethylene (C₂H₄) as a carbon source
464 [72]. Figures 8(a) through (c) summarize our analysis of the 1-LG obtained from 1µm Ni(100)
465 films, in good agreement with the analysis of the 1-LG obtained from Ni(111) and Ni(110), as
466 discussed above.

467

468 Explaining the differences between thick and thin Ni films that lead to successful monolayer
469 growth in thin films is an ongoing work that will be reported elsewhere. The different behavior may
470 be because the top and bottom surfaces are no longer isolated from one another and may
471 mutually interact. Therefore, the energy renormalizations related to the C-Ni and Ni-Ni bonds
472 would no longer be local. This could change the activation energies for the diffusions into bulk
473 and across the surface, the surface energies and adsorption energies. Another possibility is that
474 the total amount of carbon dissolved in the Ni film is proportional to the thickness, so less carbon
475 would then segregate to the surface in thinner films.



477
 478 **Figure 8.** (a) Optical image of the 1-LG obtained for Ni(100) films with thickness around $1\mu\text{m}$ using fast cool
 479 down approaches starting at $T=1000\text{ }^\circ\text{C}$. (b) Top panel: Raman spectrum of the 1-LG imaged in (a). Bottom
 480 panel: for comparison, the Raman spectrum of the M-LG obtained for the Ni(100) single crystal discussed
 481 in the previous section. (c) Optical transmittance across the wavelength range of 400-800 nm for 1-LG films
 482 grown from $1\mu\text{m}$ thick Ni(100) films.
 483

484 **Non-occurrence of carbon structures at low temperatures ($T < 800\text{ }^\circ\text{C}$)**

485 For the three studied crystallographic directions, no carbon structures were grown below $790\text{ }^\circ\text{C}$
 486 with gas flow rates of 1000 sccm for H_2 and 100 sccm for CH_4 and an exposure time of 300 sec
 487 followed by rapid quenching. The lack of carbon structure formation is mainly due to the decrease
 488 in the methane reactivity rate as the temperature decreases. A decrease in temperature of about
 489 $200\text{ }^\circ\text{C}$ results in the decrease of CH_4 reactivity by more than an order of magnitude [26]. One
 490 way to overcome this decreased reactivity would be to increase the exposure time (or
 491 equivalently, to increase the concentration of CH_4). The use of other hydrocarbons for graphene
 492 growth at temperatures lower than $800\text{ }^\circ\text{C}$ on Ni has been reported by several authors [13, 14,
 493 46, 47]. Even though diffusion into the bulk, diffusion across the surface and segregation also
 494 dramatically decrease below $790\text{ }^\circ\text{C}$, we do not believe that this limits the growth, since these
 495 processes have been observed to occur at temperatures as low as $350\text{ }^\circ\text{C}$. [1, 16]
 496

497 **CONCLUSIONS**

498
 499 In this combined experimental-theoretical study, we have demonstrated that Ni(111) and Ni(110)
 500 can be efficiently used to grow single-layer graphene (1-LG) under ambient pressure CVD, over
 501 areas on the order of a few cm^2 . Upon transferring the films to dielectric substrates, our
 502 measurements confirm the presence of 1-LG on Ni(111) and Ni(110). Using the same gas flow
 503 rates and growth times, different temperatures are needed to grow 1-LG on Ni(111) ($T=(1000\pm 1)$
 504 $^\circ\text{C}$) and on Ni(110) ($T=(800\pm 1)\text{ }^\circ\text{C}$). We have also performed DFT calculations to suggest
 505 atomistic models to explain the growth of graphene on the different low-index surfaces. We
 506 propose that crystal symmetry, adsorption energies, diffusion across, diffusion into, segregation,
 507 and dimer formation are the key factors needed to formulate a description of the first stages of
 508 graphene growth. For Ni(100) the formation of 1-LG is not favored by symmetry and is also
 509 adversely affected by the very strong and localized Ni-C bonds that inhibit C-C dimer formation.
 510 However, we show that M-LG can be formed on Ni(100), in disagreement with previous
 511 predictions suggesting that organized carbon structures on Ni(100) were unlikely or not possible.
 512 Therefore our discussion is very relevant to current research efforts in graphene fabrication and

513 applications, especially when low temperature growth is desirable. Although only M-LG was
514 obtained on Ni(100) single crystals, with 1-LG obtained for 1 μ m thick thin films, complementing
515 recent results by Zou *et al.* [72]. Due to the ease of multilayer growth on Ni, this study shows
516 promise for extension to control the number of layers formed on different Ni surfaces, an added
517 benefit for different technological applications.

518

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522

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524

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534

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